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U.S. Patent Application Serial No. 10/517,765
Reply to OA dated December 1, 2008

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

Claims 1 -8 (Cancel)

Claim 9 (Currently Amended): A substrate treating apparatus comprising a processing chamber for processing ~~at least one substrate~~ substrates, and a substrate support member for supporting said ~~at least one substrate~~ substrates in said processing chamber, wherein said substrate support member has multiple holding members installed vertically, each of said holding members has multiple support grooves, each of said support grooves contains a support section, formed as a protrusion on the substrate support member and arranged to contact said substrate, and a receiving section formed below said support section and extending outwards from a section of the outer periphery of said support section, and said receiving section extends between outwards to 6 mm and 15 mm or more from a section of the outer periphery of said support section.

Claims 10 - 18 (Cancel)

Claim 19 (New): The substrate treating apparatus according to claim 9, wherein said receiving section extends outwards between 6mm and 15 mm from a section of the outer periphery

U.S. Patent Application Serial No. 10/517,765
Reply to OA dated December 1, 2008

of said support section.

Claim 20 (New): The substrate treating apparatus according to claim 9, wherein said receiving section extends outwards to 10 mm or more from a section of the outer periphery of said support section.

Claim 21 (New): The substrate treating apparatus according to claim 9, wherein said receiving section extends outwards between 10 mm and 15 mm from a section of the outer periphery of said support section.

Claim 22 (New): The substrate treating apparatus according to claim 9, wherein said receiving section is formed in a right-angled parallel-piped shape with a rectangular shape as seen from a plan view, and said receiving section is formed in a flat plate with a rectangular shape as seen from a plan view.

Claim 23 (New): The substrate treating apparatus according to claim 9, wherein said support section is arranged inside the outer periphery of said receiving section as seen from a plan view.

Claim 24 (New): A substrate treating apparatus comprising a processing chamber for processing substrates, and a substrate support member for supporting said substrates in said

U.S. Patent Application Serial No. 10/517,765

Reply to OA dated December 1, 2008

processing chamber, wherein said substrate support member has multiple holding members installed vertically, each of said holding members has multiple support grooves, each of said support grooves contains a support section to contact said substrate, and a receiving section formed below said support section and extending outwards from a section of the outer periphery of said support section, said support section is formed in a flat plate with a mountain shape as seen from a plan view, and the width of said support section becomes narrower as it approaches the center of said substrate.

Claim 25 (New): The substrate treating apparatus according to claim 24, wherein said support section is arranged inside the outer periphery of said receiving section as seen from a plan view.

Claim 26 (New): The substrate treating apparatus according to claim 24, wherein each of said holding members has a columnar shape.

Claim 27 (New): A substrate treating apparatus comprising a processing chamber for processing substrates, and a substrate support member for supporting said substrates in said processing chamber, wherein said substrate support member has multiple holding members installed vertically, each of said holding members has multiple support grooves, each of said support grooves contains a support section to contact said substrate, and a receiving section formed below said support section and extending outwards from a section of the outer periphery of said support section, said support section is formed in a flat plate with a trapezoidal shape as seen from a plan view, and

U.S. Patent Application Serial No. **10/517,765**
Reply to OA dated December 1, 2008

the width of said support section becomes narrower as it approaches the center of said substrate.

Claim 28 (New): The substrate treating apparatus according to claim 27, wherein said support section is arranged inside the outer periphery of said receiving section as seen from a plan view.

Claim 29 (New): The substrate treating apparatus according to claim 27, wherein each of said holding members has a columnar shape.